

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: HATTORI, Kazuhiro

Group Art Unit: 1765

Serial No.: 09/816,784

Examiner: Lan Vinh

Filed: March 26, 2001

P.T.O. Confirmation No.: 5542

For:

DRY ETCHING METHOD, MICROFABRICATION

PROCESS AND DRY ETCHING MASK

INFORMATION DISCLOSURE STATEMENT PURSUANT TO 37 CFR 1.97(b)

Commissioner for Patents Washington, D.C. 20231

GROUP TOO 2003

Sir:

The attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached Form PTO-1449. One copy of each of these documents is attached.

No fee or certification is required in connection with this Information Disclosure Statement, since it is being submitted prior to the issuance of a first official action on the merits or expiration of the three month period following the filing date or the entry of the national stage of the abovecaptioned application.

The above information is presented so that the Patent and Trademark Office can, in the first instance, determine any materiality thereof to the claimed invention. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the documents cited in the attached Form PTO-1449 be made of record therein and appear on the first page of any patent to issue therefrom.

The Commissioner is authorized to charge our Deposit Account No. 01-2340 for any fee which is deemed by the Patent and Trademark Office to be required to effect consideration of this GROUN TOO statement.

Respectfully submitted,

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PATENT TRADEMARK OFFICE

Enclosures: PTO-1449 and references (3)